

<b>Notice of References Cited</b>	Application/Control No. 10/729,723		Applicant(s)/Patent Under Reexamination KIM ET AL.	
	Examiner Samuel A. Turner		Art Unit 2877	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-5,112,129	05-1992	Davidson et al.	356/497
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

#### FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Fast thickness profile measurement using a peak detection method based on an acousto-optic tunable filter, Kim et al, Measurement Science and Technology, 5/2002, pp L1-L5.
	V	Measurement of the thickness profile of a transparent thin film deposited upon a pattern structure with an acousto-optic tunable filter, Kim et al, Optics Letters, 11/2002, pp 1893-1895.
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.